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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE EXAMINING
GROUP 1763

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

TAKAHIRO Horiguchi et al

: EXAMINER: KACKAR, RAM N.

SERIAL NO: 09/855,493

:

FILED: MAY 16, 2001

: GROUP ART UNIT: 1763

FOR: SINGLE-SUBSTRATE-PROCESSING:
APPARATUS FOR SEMICONDUCTOR
PROCESS

AMENDMENT UNDER 37 C.F.R. §1.116

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action dated December 17, 2002, please amend the above-identified patent application as follows:

IN THE CLAIMS

Please amend the claims to read as shown below:

21. (Amended) A single-substrate-processing apparatus, comprising:

an airtight process chamber including a casing and configured to process a target substrate;

a worktable configured to support the target substrate within the casing of the process chamber,